

Donyau Chiang

List of Publications by Year in descending order

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56
papers

518
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949033

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759306

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56
all docs

56
docs citations

56
times ranked

780
citing authors

#	ARTICLE	IF	CITATIONS
1	Onset of hard magnetic MnGa thin film on glass substrate. Journal of Magnetism and Magnetic Materials, 2021, 524, 167668.	1.0	3
2	Laser Markings on Transparent Materials Using Nanosecond-Pulse Laser. , 2018, , .		1
3	Effect of electron-beam deposition process variables on the film characteristics of the CrOx films. AIP Advances, 2018, 8, 025016.	0.6	2
4	Surface modification nanoporous titanium oxide films using continuous wave CO2 laser. Applied Physics A: Materials Science and Processing, 2016, 122, 1.	1.1	4
5	Optical properties and crystallinity of silver mirrors under a 35 krad cobalt-60 radiation. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2015, 33, 05E104.	0.9	1
6	Effect on structural, optical and electrical properties of aluminum-doped zinc oxide films using diode laser annealing. Optics and Laser Technology, 2015, 68, 41-47.	2.2	16
7	Effect of substrate temperature on the properties of ZrB ₂ film on Si(111) deposited by pulsed DC magnetron sputtering. Japanese Journal of Applied Physics, 2014, 53, 095503.	0.8	8
8	Head-up display using an inclined Al ₂ O ₃ column array. Applied Optics, 2014, 53, A121.	0.9	5
9	FTO films deposited in transition and oxide modes by magnetron sputtering using tin metal target. Applied Optics, 2014, 53, A148.	0.9	8
10	Dual-photoresist complementary lithography technique for the formation of submicron patterns on sapphire substrates. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2014, 13, 033004.	1.0	1
11	Methanol desorption in poly(methyl methacrylate) with stress distributions. Journal of Materials Research, 2014, 29, 2162-2169.	1.2	4
12	Investigation of the ablation of fluorine-doped tin oxide thin films by square top-hat ultraviolet laser beams. Optics and Lasers in Engineering, 2014, 52, 212-217.	2.0	10
13	Conductive and transparent multilayer films for low-temperature TiO ₂ /Ag/SiO ₂ electrodes by E-beam evaporation with IAD. Nanoscale Research Letters, 2014, 9, 35.	3.1	41
14	WO ₃ Electrochromic Thin Films Doped With Carbon. IEEE Transactions on Magnetics, 2014, 50, 1-4.	1.2	2
15	Investigation on optical and electrical properties of ZnO sandwich structure with metal interlayer. Japanese Journal of Applied Physics, 2014, 53, 05FF05.	0.8	4
16	Investigation of the Microstructure, Porosity, Adhesion, and Optical Properties of a WO ₃ Film Fabricated Using an E-Beam System With Ion Beam-Assisted Deposition. IEEE Transactions on Magnetics, 2014, 50, 1-4.	1.2	2
17	Fabrication of highly ordered nanohoneycomb (ZnO/Pt) arrays. International Journal of Nanotechnology, 2014, 11, 1047.	0.1	0
18	Dual photoresist complimentary lithography technique produces sub-micro patterns on sapphire substrates. , 2014, , .		0

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19	Dual layer photoresist complimentary lithography applied on sapphire substrate for producing submicron patterns. <i>Microsystem Technologies</i> , 2013, 19, 1745-1751.	1.2	1
20	Electrode patterning on PEDOT:PSS thin films by pulsed ultraviolet laser for touch panel screens. <i>Applied Physics A: Materials Science and Processing</i> , 2013, 112, 41-47.	1.1	40
21	Temperature profile of the multilayer structure irradiated by pulsed laser. <i>Applied Physics A: Materials Science and Processing</i> , 2013, 110, 571-578.	1.1	4
22	Physical properties of an oxide photoresist film for submicron pattern lithography. <i>Thin Solid Films</i> , 2013, 542, 409-414.	0.8	3
23	Submicron-size patterning on the sapphire substrate prepared by nanosphere lithography and nanoimprint lithography techniques. <i>Metals and Materials International</i> , 2013, 19, 869-874.	1.8	3
24	Electrode patterning and annealing processes of aluminum-doped zinc oxide thin films using a UV laser system. <i>Optics and Lasers in Engineering</i> , 2013, 51, 15-22.	2.0	20
25	Surface property study of different patterning sapphire structures by ICP-RIE. , 2013, , .		0
26	The tensile force oscillation of polycarbonate at elevated temperatures. <i>Polymer Engineering and Science</i> , 2013, 53, 589-596.	1.5	11
27	Microhole machining of silicon wafer in air and under deionized water by pulsed UV laser system. <i>Applied Physics A: Materials Science and Processing</i> , 2013, 110, 565-570.	1.1	4
28	Transfer of a continuous-relief lenticular array onto a quartz substrate by using SIL combined with the dry-etching method. <i>Journal of Micromechanics and Microengineering</i> , 2013, 23, 035021.	1.5	0
29	Edge Isolation of Transparent Conductive Polymer (TCP) Thin Films on Flexible Substrates using UV Laser Ablation. <i>Journal of Nanoscience and Nanotechnology</i> , 2012, 12, 4905-4910.	0.9	0
30	Monitoring on dry vacuum pump characteristics by mobile device. , 2012, , .		3
31	Binary blazed grating based on autostereoscopic display mechanism. <i>Applied Optics</i> , 2012, 51, 877.	0.9	4
32	The Sub-Micron Hole Array in Sapphire Produced by Inductively-Coupled Plasma Reactive Ion Etching. <i>Journal of Nanoscience and Nanotechnology</i> , 2012, 12, 1641-1644.	0.9	5
33	High positioning accuracy of a dual-axis feeding system enhanced by using error compensation methods for UV laser processing system. , 2011, , .		0
34	Mechanical Properties of Pt-Ir and Ni-Ir Binary Alloys for Glass-Molding Dies Coating. <i>Journal of Nanoscience and Nanotechnology</i> , 2011, 11, 8682-8688.	0.9	22
35	The optical measurement on the CVD silica film deposited on a fused quartz substrate. <i>Physics Procedia</i> , 2011, 19, 385-390.	1.2	3
36	Fabrication of electrodes on the aluminum doped zinc oxide thin films using an ultraviolet laser direct-patterning technology. <i>Physics Procedia</i> , 2011, 19, 456-465.	1.2	5

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37	Crystallization Behavior of the AgInSbTe Film. IEEE Transactions on Magnetics, 2011, 47, 551-555.	1.2	0
38	Deep Dry Etching Patterned Silicon Using GeSbSnOx Thermal Lithography Photoresist. IEEE Transactions on Magnetics, 2011, 47, 560-563.	1.2	8
39	Mechanical and optoelectric properties of post-annealed fluorine-doped tin oxide films by ultraviolet laser irradiation. Applied Surface Science, 2011, 257, 7204-7209.	3.1	30
40	The effect of laser patterning parameters on fluorine-doped tin oxide films deposited on glass substrates. Applied Surface Science, 2011, 257, 8813-8819.	3.1	32
41	Crystallization mechanisms and recording characteristics of Si/CuSi bilayer for write-once blu-ray disc. Applied Physics Letters, 2011, 99, .	1.5	9
42	Effects of Ammonia/Methane Mixtures on Characteristics of Plasma Enhanced Chemical Vapor Deposition n-Type Carbon Films. Journal of the Electrochemical Society, 2011, 159, D77-D83.	1.3	9
43	Modeling of exact viscoelastic stresses in bilayer systems due to thermal and/or lattice mismatch: Maxwell model. Journal of Materials Research, 2011, 26, 1392-1398.	1.2	1
44	Laser scribing of indium tin oxide (ITO) thin films deposited on various substrates for touch panels. Applied Surface Science, 2010, 257, 1487-1494.	3.1	85
45	Modeling of relaxation of viscoelastic stresses in multi-layered thin films/substrate systems due to thermal mismatch. Thin Solid Films, 2010, 518, 7497-7500.	0.8	6
46	The development of an automatic scanning path generation method for the spinneret test. Proceedings of SPIE, 2010, , .	0.8	2
47	A luminance inspector used for in-line backlight module quality assurance. , 2010, , .		1
48	Zinc Oxide Column Rod Array Prepared by Inductively Coupled Plasma-Reactive Ion Etching Technology. , 2010, , .		1
49	The optical constants of thin films calculated from reflectance and transmittance measurements. , 2009, , .		0
50	The optical constants of thin films calculated from reflectance and transmittance measurements. Proceedings of SPIE, 2009, , .	0.8	2
51	A Te-free phase change media with wider recording range. IEEE Transactions on Magnetics, 2005, 41, 1028-1030.	1.2	0
52	Kinetic Crystallization Behavior of Phase-Change Medium. Japanese Journal of Applied Physics, 1999, 38, 1649-1651.	0.8	23
53	Impression creep of lead. Journal of Materials Research, 1994, 9, 903-908.	1.2	40
54	Impression creep of ABS polymers. Polymer, 1994, 35, 4103-4109.	1.8	24

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55	Compression creep of ABS polymers. <i>Polymer</i> , 1994, 35, 4110-4114.	1.8	5
56	Thermally activated deformation of polymers. Comments on a paper by Zhu and Zhu. <i>Polymer</i> , 1994, 35, 4702.	1.8	0